



CP 2823

JPW

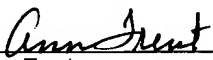
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Antonio L. P. Rotondaro Docket No: TI-31133
Serial No: 10/001,483 Conf. No: 1903
Examiner: Michelle Estrada Art Unit: 2823
Filed: 11/01/2001
For: METHOD TO IMPROVE THE UNIFORMITY AND REDUCE THE SURFACE ROUGHNESS
OF THE SILICON DIELECTRIC INTERFACE

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 11-23-04.


Ann Trent

Dear Sir:

Responsive to the Office Action mailed August 5, 2004, in connection with the above identified application, Applicant respectfully submits the following amendments and remarks.